



PATENT
Customer No. 22,852
Attorney Docket No. 04329.2439

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Tetsuro NAKASUGI, et al.

Application No.: 09/669,732

Filed: September 26, 2000

For: PATTERN OBSERVATION
APPARATUS AND PATTERN
OBSERVATION METHOD

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) Group Art Unit: 2881
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) Examiner: P. Johnston
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Commissioner for Patents
Washington, DC 20231

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AMENDMENT

In reply to the Office Action dated October 9, 2002, please amend the application as follows:

IN THE SPECIFICATION:

Please amend the specification as follows:

Please replace the paragraph on page 9 lines 6-16 with the following:

The sample is charged in the following method. FIG 13 shows an example of the relationship between the acceleration voltage of the electron beam and the emission efficiency of secondary electrons. In this case, the sample is a resist, the abscissa indicates the acceleration voltage, and the ordinate indicates the emission efficiency of secondary electrons from the sample surface. The resist is positively charged with the

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